



file

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 213.007-US)

In the Application of: YE ET AL.

Serial No: 10/815,573

Filed: APRIL 1, 2004

Title: SYSTEM AND METHOD OF LITHOGRAPHY
SIMULATION

) Group Art Unit: 1756

) Before Examiner:

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is
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Date

Michiko Sites
(person signing this certificate)

Michiko Sites
Signature

FIFTH INFORMATION DISCLOSURE STATEMENT

Dear Sir:

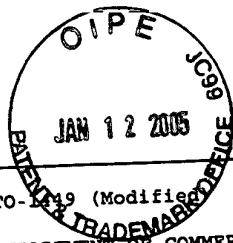
Submitted herewith is one (1) sheet of a modified Form PTO-1449. A copy of each
document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these
references formally of record with the initial Office Action.

Respectfully submitted,

Neil A. Steinberg, Reg. No. 34,735
Telephone No. 650-968-8079

Date: January 10, 2005



Sheet 1 of 1

PTO-1049 (Modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 213.007-US	SERIAL NUMBER 10/815,573
	APPLICANT(S) Ye et al.	
	FILING DATE April 1, 2004	FILING DATE 1756

U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
	5,563,702	10/1996	Emery et al.			
	5,737,072	4/1998	Emery et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	"Photomask Production Integration of KLA STARlight™ 3000 System", Kalk et al, Proc. Of SPIE, Vol. 2621, 15 th Annual BACUS Symposium on Photomask Technology and Management, December 1995, pp.112-121
	"Defect Detection and Classification in VLSI Pattern Inspection", Soo-Ik Chae, September 1987, Ph.D. Dissertation

EXAMINER	DATE CONSIDERED
EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.	